

## **LISTING OF THE CLAIMS**

This listing of claims will replace all prior versions, and listings, of claims in the application:

- 1. (Currently Amended)** A substrate processing apparatus comprising:
- a substrate processing unit for performing a predetermined process on a substrate; and
  - a substrate transfer unit for holding a container for storing substrates therein and transferring said substrates stored in said container to said substrate processing unit, wherein said substrate transfer unit includes:
    - a mounting part for mounting said container on a fixed shelf to transfer said substrates stored in said container to said substrate processing unit;
    - a first shelf line containing a plurality of first shelves arranged in a vertical direction at a first predetermined interval, each being capable of mounting said container thereon;
    - a second shelf line provided between said mounting part and said first shelf line and containing a plurality of second shelves arranged in the vertical direction at a second predetermined interval, each being capable of mounting said container thereon;
    - a displacing element having a plurality of displacing mechanisms, each of which is said plurality of displacing mechanisms being connected to a corresponding single second shelf on said second shelf line, ~~respectively, each displacing mechanism being capable of displacing said plurality of second shelves individually in the vertical direction, and each of which displaces and being configured to displace~~ the corresponding single second shelf in the vertical direction;
    - a transport element for transporting said container; and
    - a control unit configured to form a container transport path greater than said second predetermined interval in said second shelf line by displacing at least one of said plurality of second shelves in the vertical direction by said displacing element, said one of said plurality of second shelves corresponding to one of said plurality of first shelves which contains a container in said first shelf line, and configured to transport said container from said one of said plurality of first shelves to said fixed shelf in said mounting part by transporting said container through said container transport path in a horizontal direction by said transport element.

2.     **(Original)**     The substrate processing apparatus according to claim 1, wherein said displacing element is connected to at least part of said plurality of second shelves for displacing said at least part of said plurality of second shelves in the vertical direction.

3.     **(Canceled)**

4.     **(Previously Presented)**     The substrate processing apparatus according to claim 1, wherein  
the number of shelves in said second shelf line is less than that of shelves in said first shelf line in the vertical direction, and  
displacement of said plurality of second shelves is performed by said displacing element within the height of said first shelf line in the vertical direction.

5.     **(Original)**     The substrate processing apparatus according to claim 4, wherein  
the number of shelves in said second shelf line is less by one than that of shelves in said first shelf line in the vertical direction, and  
the amount of displacement of each of said plurality of second shelves performed by said displacing element corresponds to said second predetermined interval.

6.     **(Canceled)**